

Notice of References Cited	Application/Control No. 10/519,700		Applicant(s)/Patent Under Reexamination KRULL, WADE A.	
	Examiner MAKI A. ANGADI		Art Unit 1792	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-3,607,449 A	09-1971	Tokuyama et al.	438/535
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
1	U	J. Sc hmitz et al. Ultra-shallow junction formation by outdiffusion from implanted oxide, IEEE (1988)			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.